

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

765
11/11/03

Applicant(s): Chih-Ming Ke

Application No.: 10/047,266 (CONF 4511)

Filed: 1/14/2002

Title: Reducing photoresist shrinkage via plasma treatment

Attorney Docket No.: 67,200-641

Group Art Unit:
1765

Examiner:
Kin Chan Chen

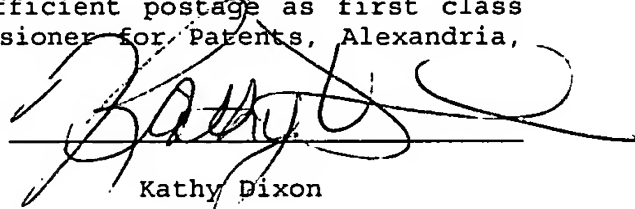
Commissioner for Patents
Alexandria, VA 22313-1450

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313.

Date:

Oct. 24, 2003


Kathy Dixon

RESPONSE TO NOTICE OF NON-COMPLIANT AMENDMENT

Dear Sir:

In response to a Notice of Non-Compliant Amendment dated October 17, 2003, attached is a complete listing of the claims.